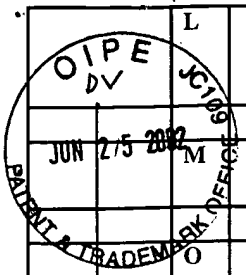
		FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE TRADEMARK & PATENT OFFICE		ATTY. DOCKET NO. S99-190		SERIAL NO. 09/710,489				
LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Kenneth A. Honer						
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U.S. PATENT DOCUMENTS										
EXAMINER INITIAL		DOCUMENT NUMBER						DATE	NAME	RELEVANT INFORMATION
	A									
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FOREIGN PATENT DOCUMENTS										
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									YES	NO
	I									
	J									
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)										
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